

Sensors and Materials

Special Issue on Advances in Devices and Materials for Stress-Strain Sensing

Call for Papers

The large piezoresistance coefficient of single-crystal silicon was discovered by Smith in 1954. Since then, the piezoresistance in various types of advanced materials has been widely used as a stress-strain sensing element in micro-electromechanical systems (MEMS). Furthermore, to investigate physical origin of the piezoresistance, multi-scale simulations for various types of advanced materials based on discrete first-principles electronic band structure and continuum micromechanics have been carried out. This special issue will focus on state-of-the-art multi-scale stress-strain sensing technologies that use advanced materials and devices.

Scope:

- stress-strain sensing
- advanced materials and devices
- piezoresistance
- first-principles calculation
- micromechanics

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